

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Chih-Chien Liu

Serial No: 09/991,196

Confirmation No.: 3908

Filed: November 20, 2001

For: HIGH DENSITY PLASMA  
CHEMICAL VAPOR DEPOSITION  
PROCESS

Art Unit: 1796

Examiner: Sergeant, Rabon A.

**AMENDMENT**

Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This amendment accompanies a request for continued examination and is filed in response to the final Office Action dated October 18, 2007, the time for response to which is extended two months by the accompanying petition from January 18, 2008 to March 18, 2008. Please amend and reconsider the above-referenced application as follows:

**The claims** are listed beginning on page 2 of this paper.

**Remarks** begin on page 9 of this paper.

I hereby certify that this correspondence  
is being transmitted via electronic filing  
to:

Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

March 18, 2008

Date of Deposit

Vivian Gutierrez

Name

*Vivian Gutierrez* 03/18/2008

Signature

Date